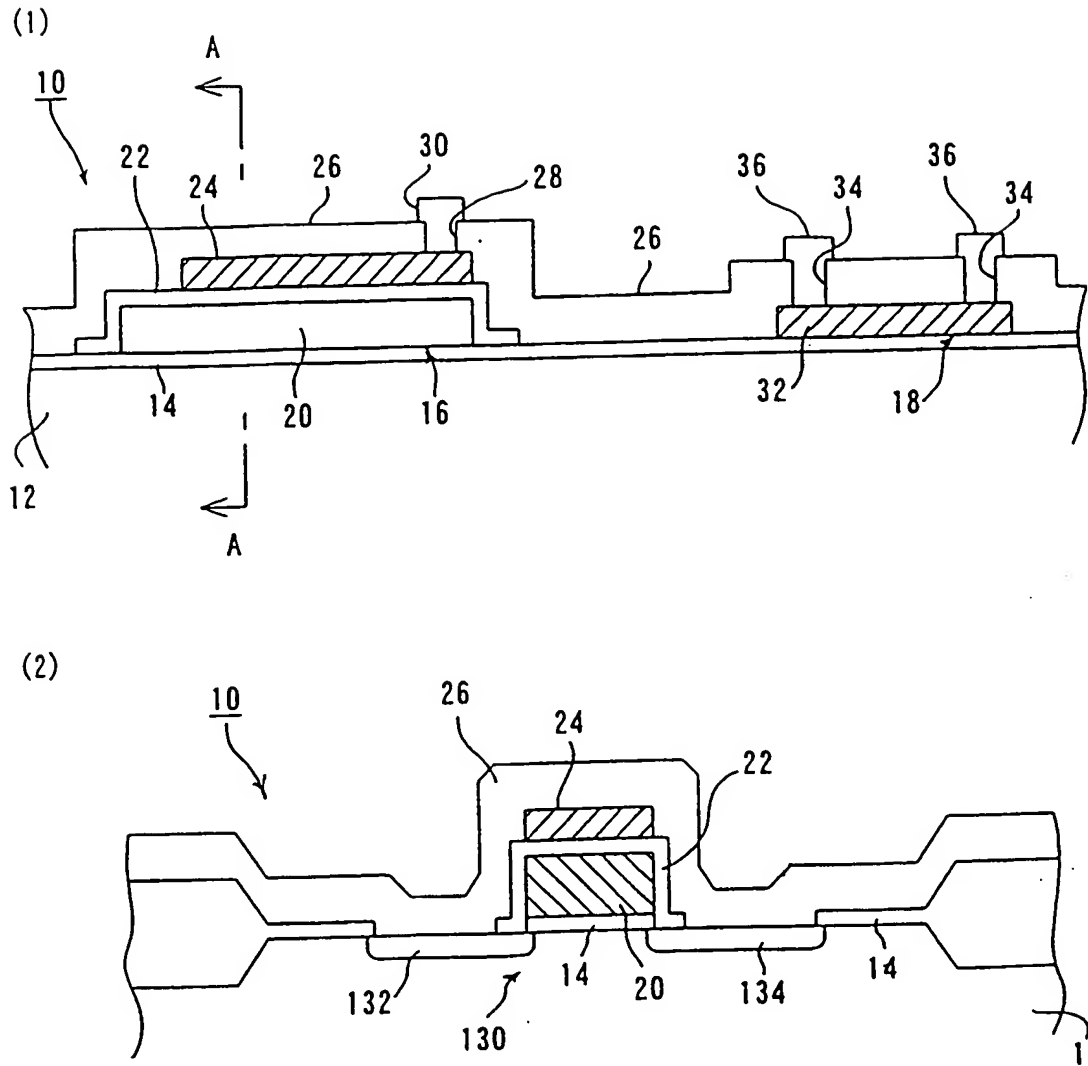


FIG. 1



- | | |
|--------------------------------|-----------------------------|
| 10: Semiconductor device | 22: Dielectric layer |
| 12: Semiconductor substrate | 24: Capacity electrode |
| 14: Insulating layer | 26: Insulating film |
| 16: Capacitive element section | 30: Drawer electrode |
| 18: Resistance element section | 32: Resistance element body |
| 20: Gate electrode | 130: MOS transistor |

FIG. 2

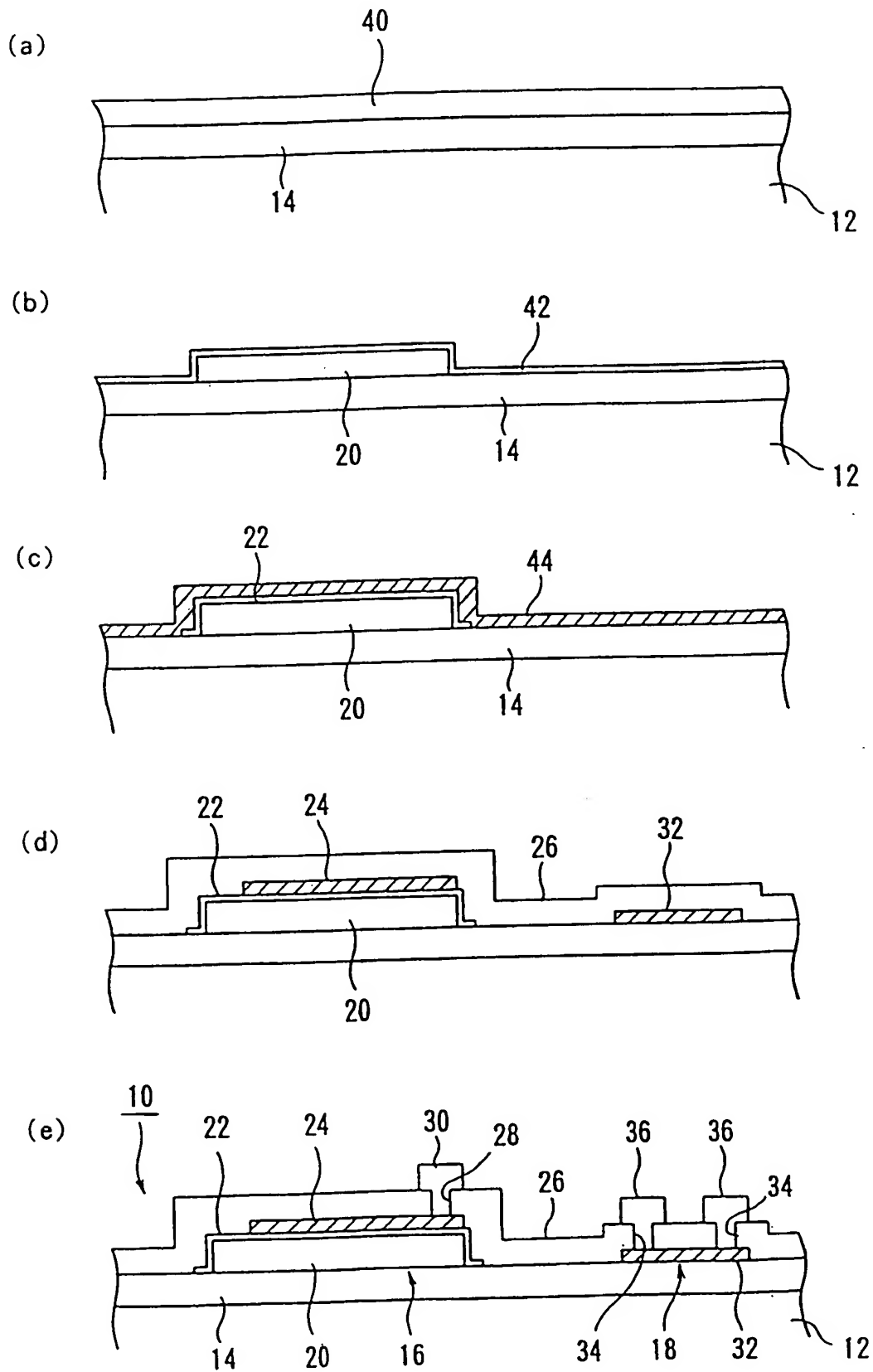


FIG. 3

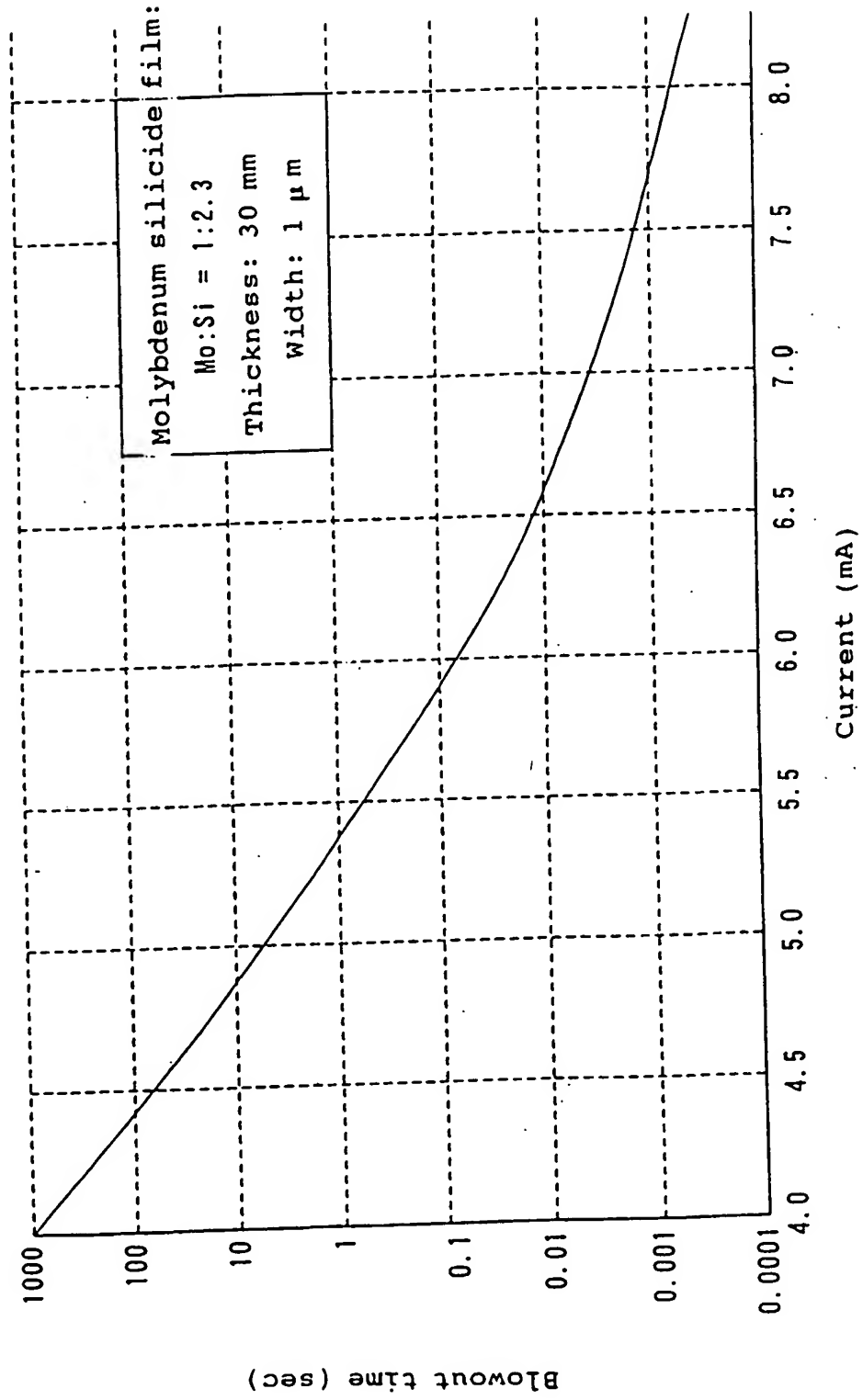


FIG. 4

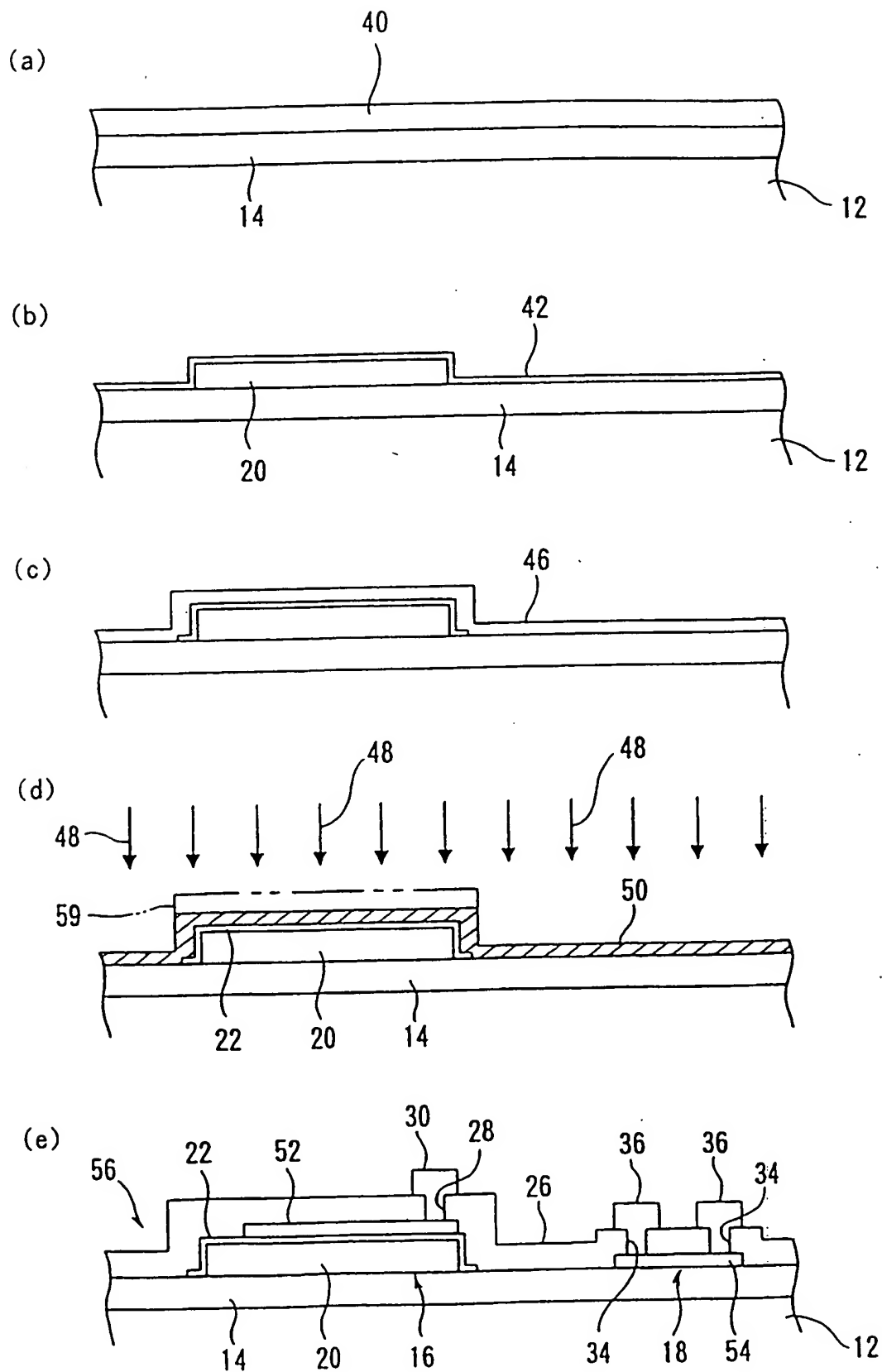


FIG. 5

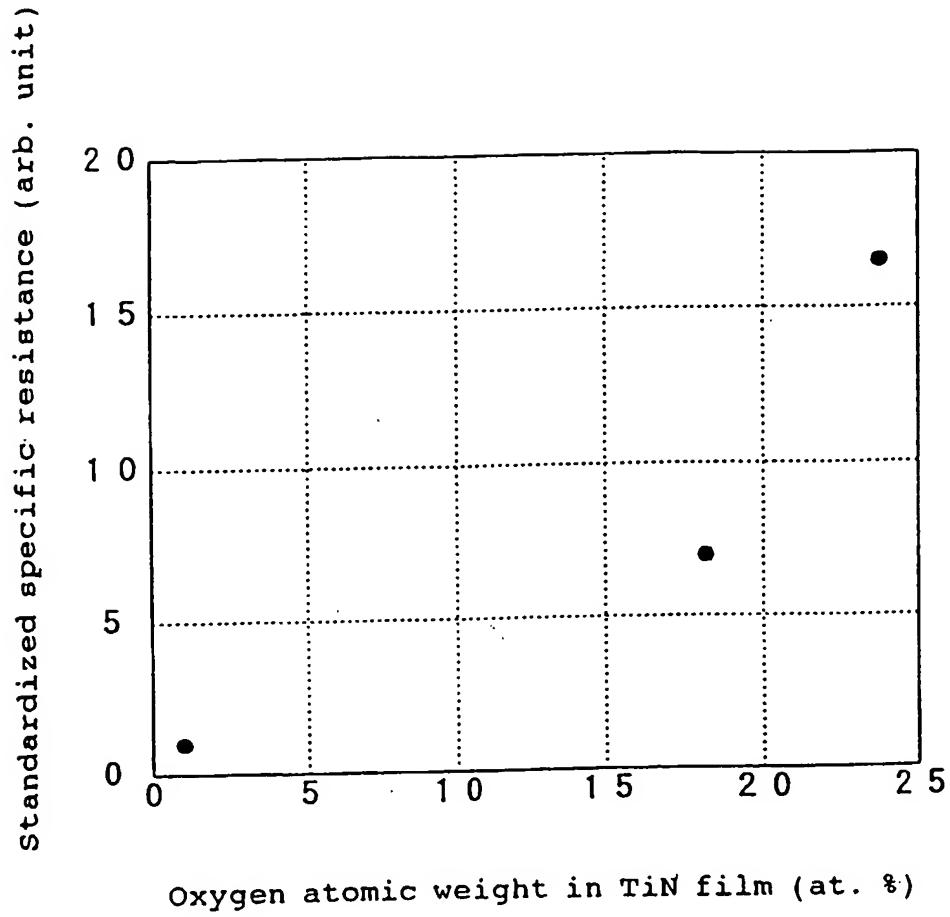


FIG. 6

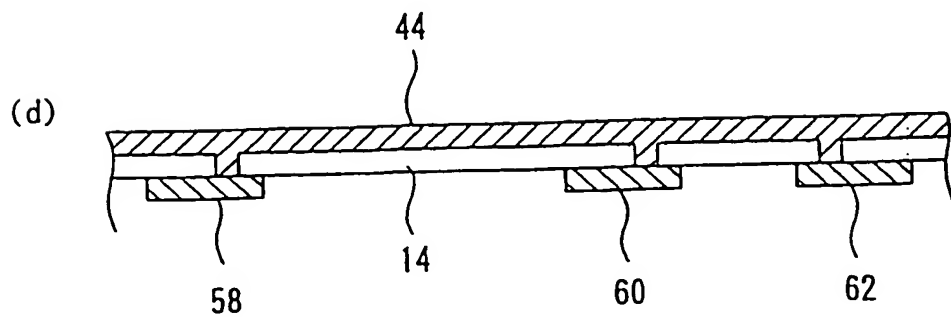
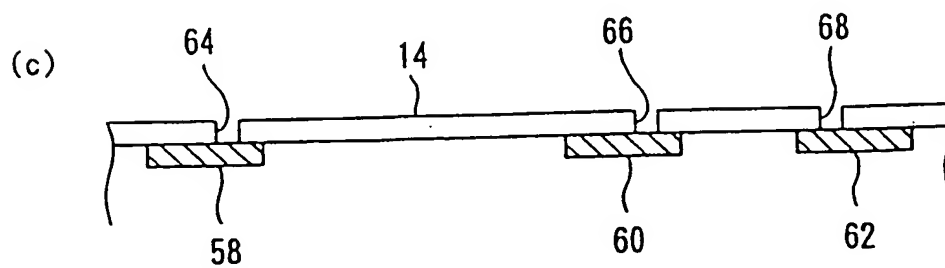
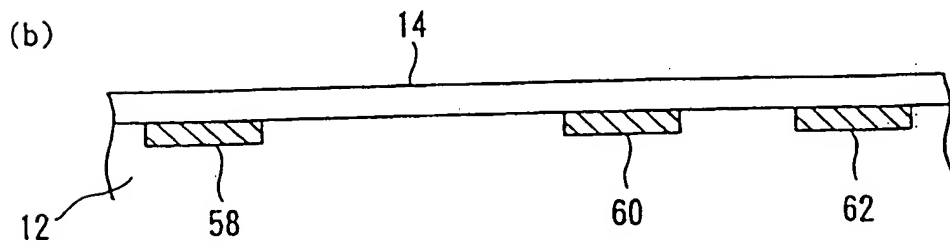
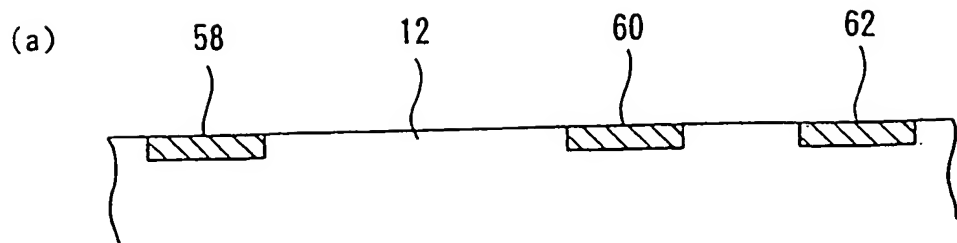


FIG. 7

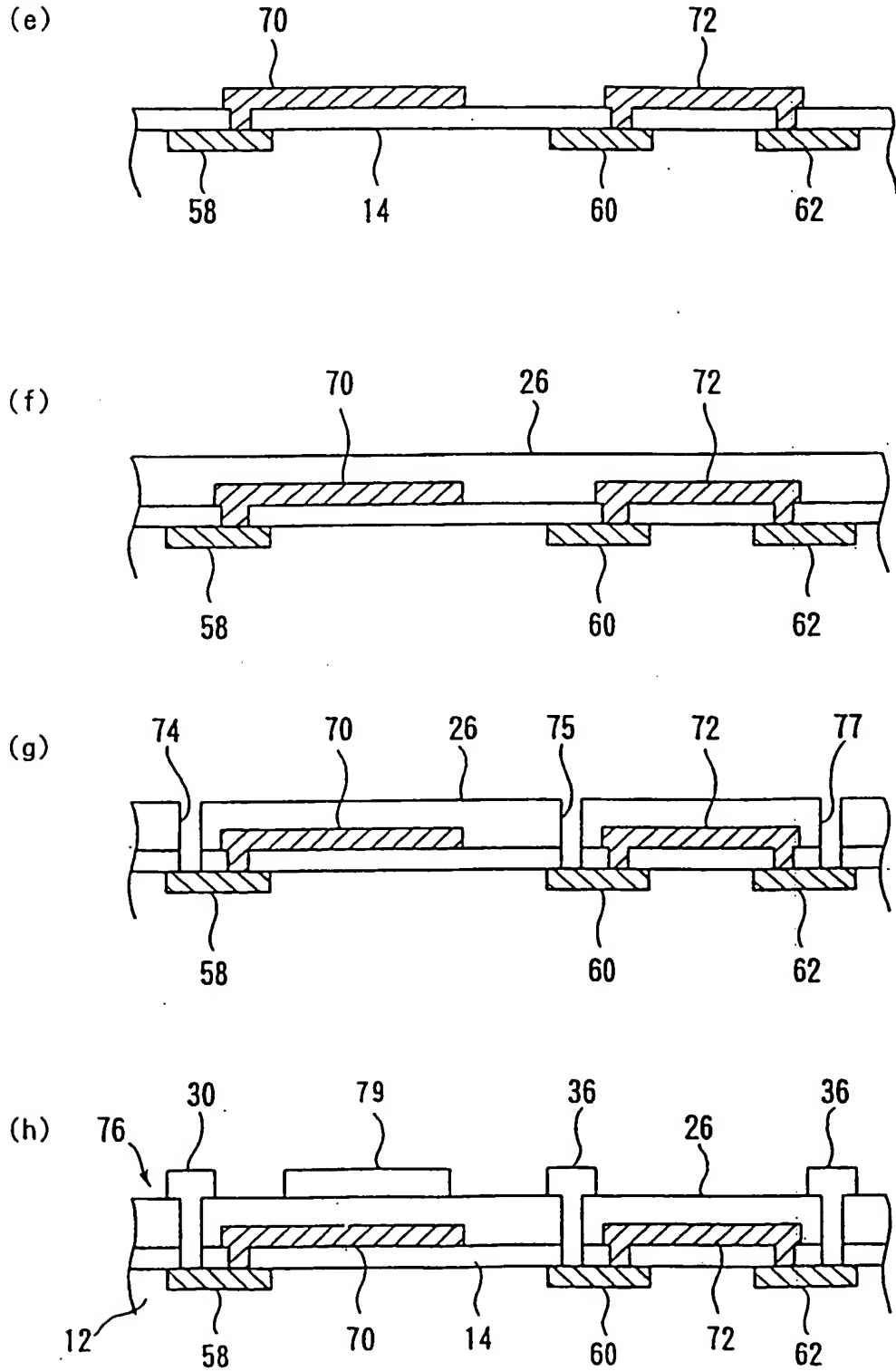


FIG. 8

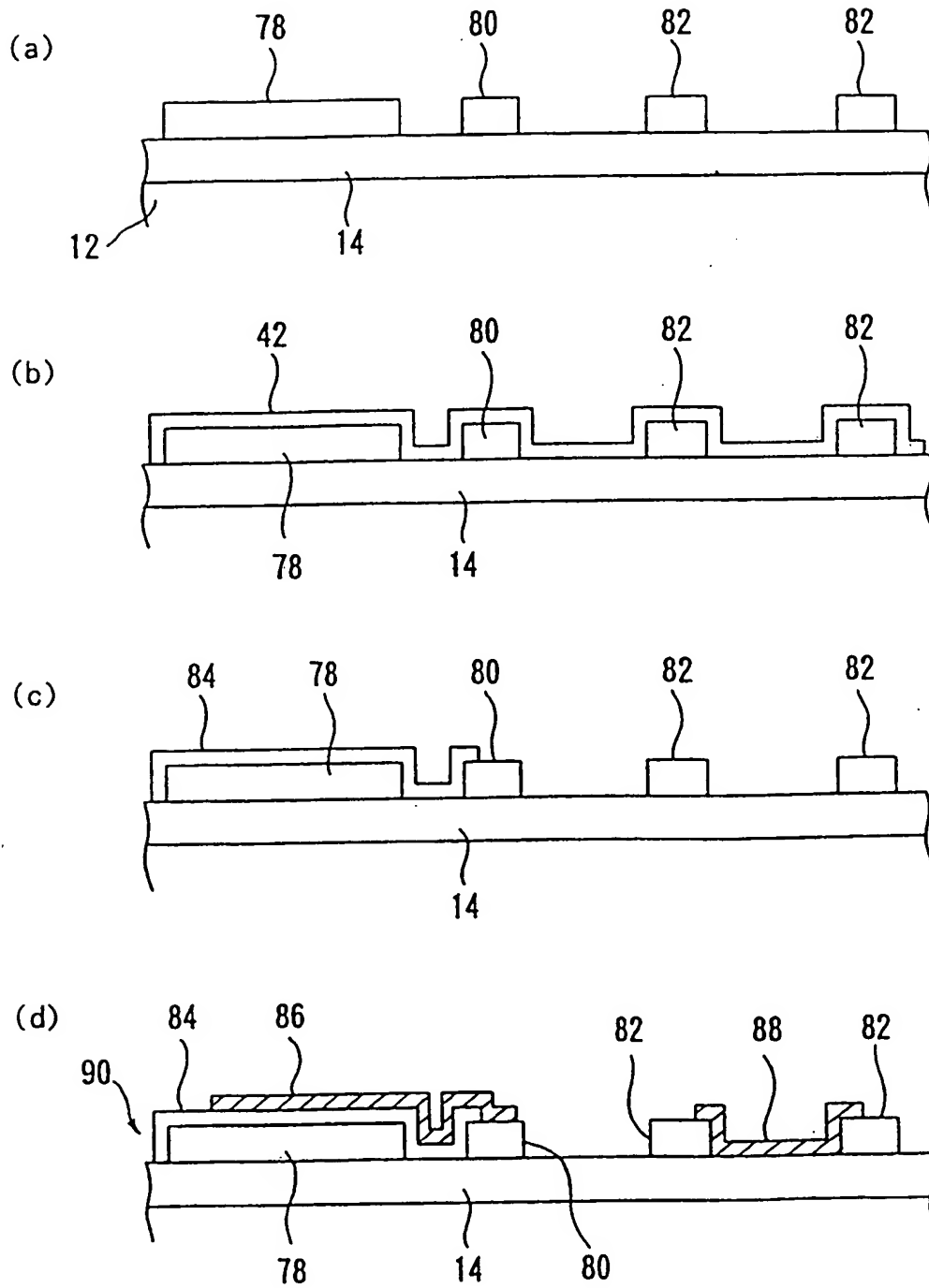


FIG. 9

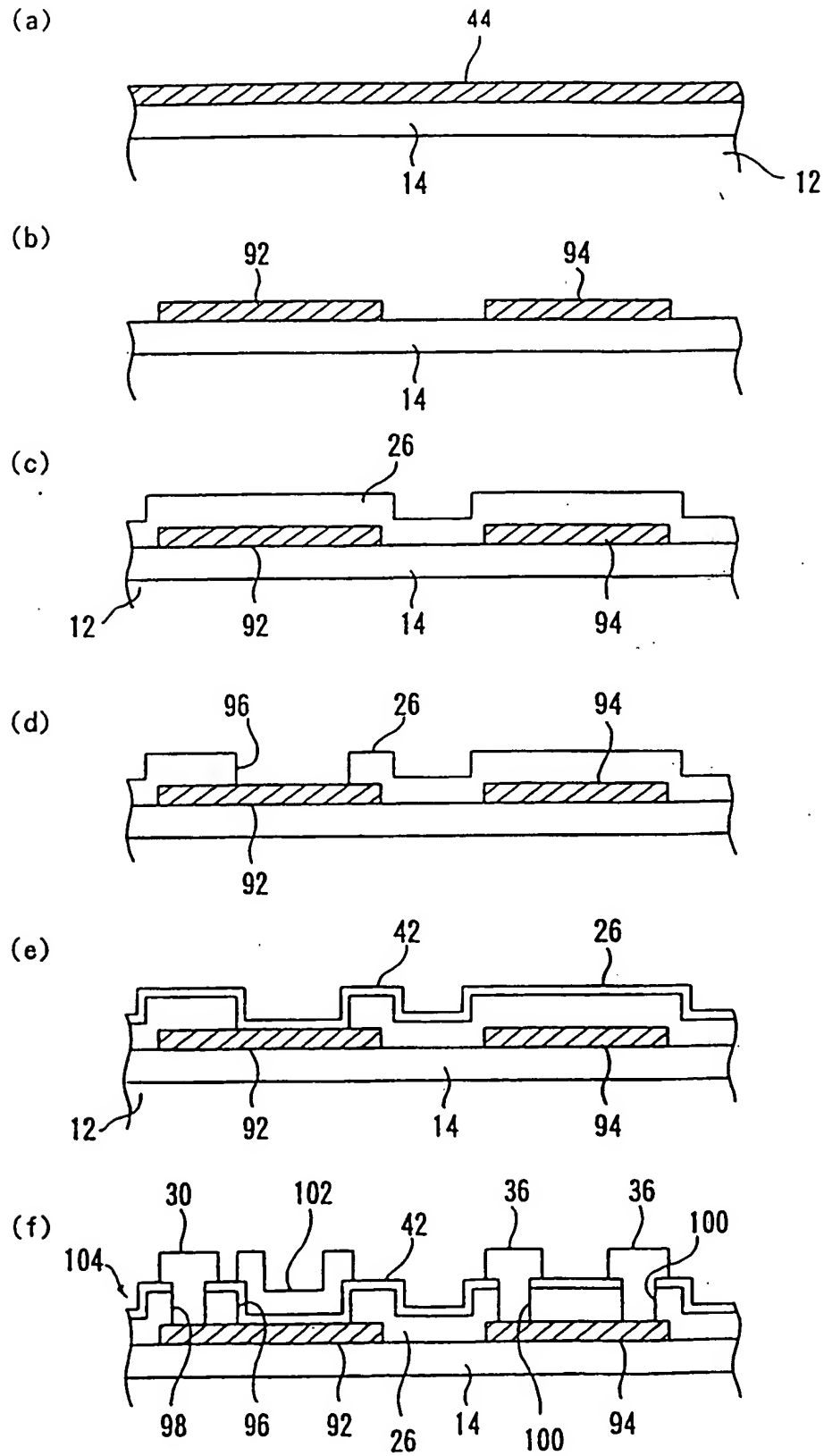


FIG. 10

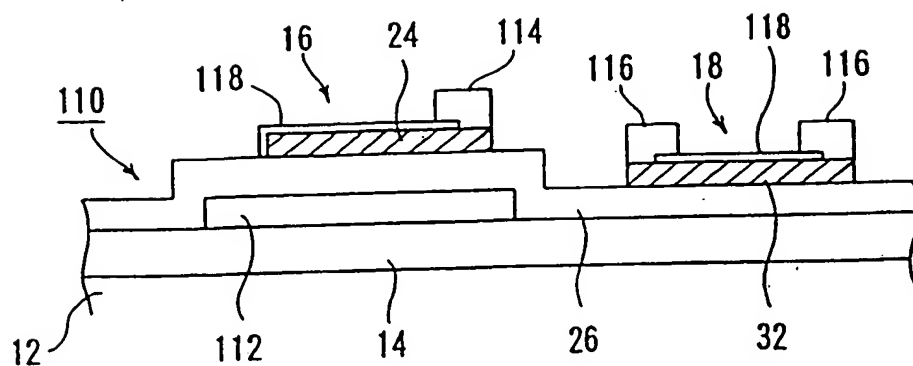


FIG. 11

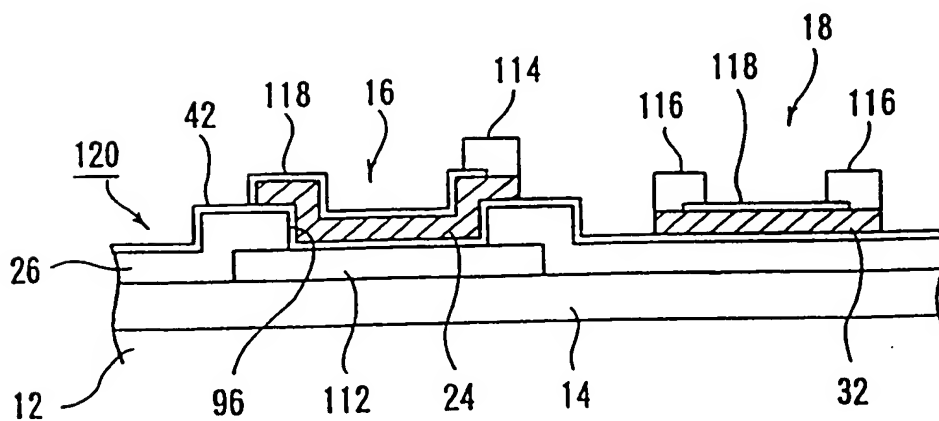


FIG. 12

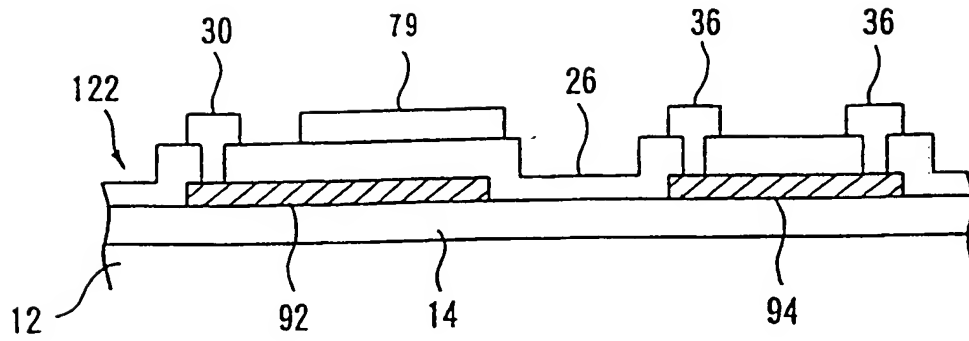


FIG. 13

